

NOV 03 2005

**CHEMICAL MECHANICAL POLISHING PROCESS**

Appl. No. : 10/711,392 Confirmation No. 5391  
Applicant : Chia-Lin Hsu,  
Teng-Chun Tsai  
Filed : September 16, 2004  
TC/A.U. : 3723  
Examiner : Jacob K. Ackun Jr.  
Docket No. : NAUP0633USA0  
Customer No. : 27765

Commissioner for Patents  
P.O. Box 1450  
Alexandria VA 22313-1450

Subject: Request for Continued Examination (RCE) in response to the advisory  
5 action mailed 10/14/2005

**INTRODUCTORY COMMENTS**

In response to the Office action identified above, a request for continued  
10 examination (RCE) is made and the above-identified application is to be amended as  
indicated in the following sections. No new matter has been introduced by these  
amendments. A continued examination and consideration of all amendments are  
politely requested.

15 **Amendments to the Claims** are reflected in the listing of claims beginning on page 2 of  
this paper.

Remarks begin on page 4 of this paper.